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OSMM&N File No. 0039-7632-0X

By: NFO/SUK/ils

Dept.: <u>:C:</u>

Serial No. <u>09/531,163</u>

In the matter of the Application of: Hirovuki YANO, et al.

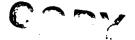
For: AQUEOUS DISPERSION, AQUEOUS DISPERION FOR CHEMICAL MECHANICAL POLISHING USED FOR MANUFACTURE OF SEMICONDUCTOR DEVICES, METHOD FOR MANUFACTURE OF SEMICONDUCTOR DEVICES, AND METHOD FOR FORMATION OF EMBEDDED WIRING

Due Date: February 19, 2004

The following has been received in the U.S. Patent Office on the date stamped hereon:

- Dep. Acct. Order Form
- PTO Cover Letter
- Request for Refund
- Copy of Pair Report (3 pages)







Docket No.: 0039-7632-0X

OBLON

SPIVAK

McClelland

MAIER

NEUSTADT

P.C.

ATTORNEYS AT LAW

COMMISSIONER FOR PATENTS ALEXANDRIA, VIRGINIA 22313

RE: Application Serial No.: 09/531,163

Applicants: Hiroyuki YANO, et al.

Filing Date: March 17, 2000

For: AQUEOUS DISPERSION, AQUEOUS DISPERION

FOR CHEMICAL MECHANICAL POLISHING USED

FOR MANUFACTURE OF SEMICONDUCTOR
DEVICES, METHOD FOR MANUFACTURE OF
SEMICONDUCTOR DEVICES, AND METHOD FOR

FORMATION OF EMBEDDED WIRING

Group Art Unit: 1765

Examiner: DEO, DUY VU NGUYEN

SIR:

Attached hereto for filing are the following papers:

Request for Refund Copy of PAIR Report (3 pages)

Our check in the amount of \$0.00 is attached covering any required fees. In the event any variance exists between the amount enclosed and the Patent Office charges for filing the above-noted documents, including any fees required under 37 C.F.R 1.136 for any necessary Extension of Time to make the filing of the attached documents timely, please charge or credit the difference to our Deposit Account No. 15-0030. Further, if these papers are not considered timely filed, then a petition is hereby made under 37 C.F.R. 1.136 for the necessary extension of time. A duplicate copy of this sheet is enclosed.

Respectfully submitted,

OBLON, SPIVAK, McCLELLAND, MAIER & NEUSTADT, P.C.

Norman F. Oblon Registration No. 24,618

Stefan U. Koschmieder, Ph.D. Registration No. 50,238

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Atty. Docket No. 0039-7632-0X

IN THE UNITED STATES PATENT & TRADEMARK OFFICE

IN RE APPLICATION OF:

Hiroyuki YANO, et al.

:EXAMINER: DEO, DUY VU

NGUYEN

SERIAL NO.: 09/531,163

:GROUP ART UNIT: 1765

FOR: AQUEOUS DISPERSION, AQUEOUS DISPERSION FOR CHEMICAL

MECHANICAL POLISHING USED FOR FANUFACTURE OF

SEMICONDUTOR DEVICES, METHOD FOR MANUFACTURE OF SEMICONDUCTOR DEVICES, AND METHOD FOR FORMATION OF

EMBEDDED WIRING

REQUEST FOR REFUND

COMMISIONER FOR PATENTS ALEXANDRIA, VIRGINIA 22313

SIR:

Pursuant to 37 CFR 1.26, Applicants request a refund of the Notice of Appeal and one month extension of time that were inadvertently paid on February 2, 2004.

REMARKS

Applicants request a refund of \$440.00 paid on February 2, 2004, for a Notice of Appeal and one month extension of time. A Notice of Allowability was indicated on January 21, 2004 as evidenced by the attached sheets, therefore the filing of the Notice of Appeal and one month extension of time were not required, and this request is believed to be justified.



Application No. 09/53 3

Please credit the refund to our Deposit Account No. 15-0030. A duplicate copy of this sheet is enclosed.

Respectfully submitted,

OBLON, SPIVAK, McCLELLAND, MAIER & NEUSTADT, P.C.

Norman F. Oblon Registration No. 24,618

Stefan U. Koschmieder, Ph.D. Registration No. 50,238

 $\begin{array}{c} \text{Customer Number} \\ 22850 \end{array}$

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Se	earch results for a			
Application Number:	09/531,163	Customer Number:	22850	
Filing or 371 (c) Date:	03-17-2000	Status:	Allowed Notice of Allow Mailed Issue Revision Completed	
Application Type:	Utility	Status Date:	02-04-2004	
Name:	DEO, DUY VU NGUYEN	Location:	ELECTRONIC	
Group Art Unit:	1765	Location Date:	01-06-2004	
Confirmation Number:	5064	Earliest Publication No:	-	
Number:	0039-7632-0X	Earliest Publication Date:	•	
Class/ Sub- Class:	438/692	Patent Number:	•	
	Hiroyuki Yano, Yokohama-shi, (JP)	Issue Date of Patent:	•	
Title Of Invention:	AQUEOUS DISPERSION, AQUEOUS DISPERSION FOR CHEMICAL MECHANICAL POLISHING USED FOR MANUFACTURE OF SEMICONDUCTOR DEVICES, METHOD FOR MANUFACTURE OF SEMICONDUCTOR DEVICES, AND METHOD FOR FORMATION OF EMBEDDED WIRING			

Select Search Option

Image File Wrapper
Foreign Priority
Patent Term Extension History
Publication Review

File History				
Number	Date	Contents Description		
72	02-04-2004	Mail Notice of Allowance		
71	01-29-2004	Issue Revision Completed		
70	01-30-2004	Notice of Allowance Data Verification Completed		
69	01-21-2004	Notice of Allowability		
68	01-14-2004	Date Forwarded to Examiner		
67	12-23-2003	Amendment after Final Rejection		
66	01-07-2004	Mail Examiner Interview Summary (PTOL - 413)		
65	12-17-2003	Examiner Interview Summary Record (PTOL - 413)		
- 65	12-17-2003	Examiner interview Summary Record (P1OL - 413)		

Search

64	12-17-2003	Examiner Interview Summary Record (PTOL - 413)	
63	10-02-2003	Mail Final Rejection (PTOL - 326)	
62	09-30-2003	Final Rejection	
61	08-04-2003	Date Forwarded to Examiner	
60	07-30-2003	Response after Non-Final Action	
59	04-30-2003	Mail Non-Final Rejection	
58	04-29-2003	Non-Final Rejection	
57	04-04-2003	Information Disclosure Statement (IDS) Filed	
56	03-14-2003	Affidavit(s) (Rule 131 or 132) or Exhibit(s) Received	
5 5	03-20-2003	Date Forwarded to Examiner	
53	03-20-2003	Date Forwarded to Examiner	
52	03-14-2003	Request for Continued Examination (RCE)	
51	03-20-2003	Express Abandonment (for Entry of CPA / RCE / Rule129)	
50	03-14-2003	Workflow - Request for RCE - Begin	
49	02-28-2003	Mail Advisory Action (PTOL - 303)	
48	02-26-2003	Advisory Action (PTOL-303)	
47	02-13-2003	Affidavit(s) (Rule 131 or 132) or Exhibit(s) Received	
46	02-21-2003	Date Forwarded to Examiner	
45	02-13-2003	Amendment after Final Rejection	
44	11-15-2002	Mail Final Rejection (PTOL - 326)	
43	11-15-2002	Final Rejection (FTOL - 326)	
42	09-24-2002	Date Forwarded to Examiner	
<u>42</u> 41			
40	09-23-2002	Response after Non-Final Action	
40 39	06-21-2002	Mail Non-Final Rejection	
	06-20-2002	Non-Final Rejection	
38 36	05-21-2002	Information Disclosure Statement (IDS) Filed	
<u> 36</u>	05-08-2002	Date Forwarded to Examiner	
35	05-03-2002	Request for Continued Examination (RCE)	
<u>34</u>	05-08-2002	Express Abandonment (for Entry of CPA / RCE / Rule129)	
33	05-03-2002	Request for Extension of Time - Granted	
32	05-03-2002	Workflow - Request for RCE - Begin	
31	04-16-2002	Mail Advisory Action (PTOL - 303)	
30	04-15-2002	Advisory Action (PTOL-303)	
29	04-11-2002	Date Forwarded to Examiner	
28	04-04-2002	Amendment after Final Rejection	
27	04-04-2002	Request for Extension of Time - Granted	
26	03-15-2002	Mail Advisory Action (PTOL - 303)	
25	03-14-2002	Advisory Action (PTOL-303)	
24	03-04-2002	Date Forwarded to Examiner	
23	02-28-2002	Amendment after Final Rejection	
22	12-04-2001	Mail Final Rejection (PTOL - 326)	
21	12-03-2001	Final Rejection	
20	10-05-2001	Information Disclosure Statement (IDS) Filed	
19	10-10-2001	Date Forwarded to Examiner	
18	10-05-2001	Response after Non-Final Action	
17	03-20-2001	Case Docketed to Examiner in GAU	
16	08-15-2001	Information Disclosure Statement (IDS) Filed	
15	07-05-2001	Mail Non-Final Rejection	
14	06-29-2001	Non-Final Rejection	
13	06-19-2001	Case Docketed to Examiner in GAU	
12	04-19-2001	Date Forwarded to Examiner	
:- 11	04-17-2001	Response to Election / Restriction Filed	
10	03-20-2001	Mail Restriction Requirement	

9	03-20-2001	-Requirement for Restriction / Election
8	07-24-2000	Information Disclosure Statement (IDS) Filed
7	07-17-2000	Information Disclosure Statement (IDS) Filed
6	06-21-2000	Request for Foreign Priority (Priority Papers May Be Included)
5	06-07-2000	Case Docketed to Examiner in GAU
4	05-31-2000	Application Dispatched from OIPE
3	05-31-2000	Correspondence Address Change
2	04-12-2000	IFW Scan & PACR Auto Security Review
1	03-17-2000	Initial Exam Team nn

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